



AF/280

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Ohtani, et al. Art Unit : 2815
Serial No.: 09/455,991 Examiner : Jose R. Diaz
Filed : December 6, 1999
Title : SEMICONDUCTOR DEVICE AND METHOD OF MANUFACTURING
THE SAME

Commissioner for Patents
Washington, D.C. 20231

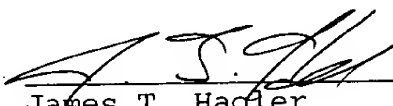
TRANSMITTAL LETTER AND PETITION FOR AUTOMATIC EXTENSION

Correspondence relating to this application is enclosed.
The required fees are computed below. Please apply any charges
not covered, or any credits, to Deposit Account No. 06-1050.

Total					
Claims	17	-	17	=	0 \$0
Independent	2	-	2	=	0 \$0
TOTAL FEE DUE					\$0

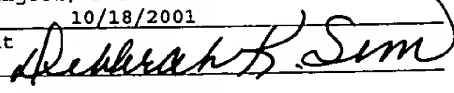
Respectfully submitted,

Date: 10/18/01


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CERTIFICATE OF MAILING BY FIRST CLASS MAIL
I hereby certify under 37 CFR §1.8(a) that this
correspondence is being deposited with the
United States Postal Service as first class mail
with sufficient postage on the date indicated
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Date of Deposit 10/18/2001
Signature 
Typed or Printed Name of Person Signing
Certificate Debbrah K. Sim



Attorney's Docket No.: 075-213002 / US3521/3522

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BOX AF

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RESPONSE

In response to the action mailed July 18, 2001, please
amend the application as follows:

In the claims:

Please amend claim 6 as follows:

rule 1
B
6. (Amended) A method of manufacturing a
semiconductor device, said method comprising:
forming an amorphous semiconductor film on an
insulating surface;
introducing a metal element being capable of
promoting crystallization of the amorphous semiconductor film to

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Deborah K. Sim

Typed or Printed Name of Person Signing
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Deborah K. Sim